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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application for:

Krishna Parat et al.

Application No.: 10/669,825

Filed: September 23, 2003

For: DUAL TRENCH ISOLATION
USING SINGLE CRITICAL
LITHOGRAPHIC PATTERNING

Examiner: Kilday, Lisa A.

Art Group: 2829

CERTIFICATE OF MAILING

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313

AMENDMENT AND RESPONSE

Dear Sir:

This communication is being submitted in response to the Office Action mailed on **September 8, 2004**. Reconsideration of the captioned application, in light of the following amendments and remarks is respectfully requested.

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.

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